09/03/08





PATENT YOR920030206US1

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

In re Application of : Larry Shungwei Mok

Serial Number : 10/784,624

Filing Date : 02/23/2004

Examiner : Tho V. Duong

Group Art Unit : 3753

For : HEAT DISSIPATION

INTERFACE FOR SEMICONDUCTOR CHIP STRUCTURES

Sir:

In response to the Official Action dated June 27, 2008, please amend the above-identified application as follows:

In the Specification:

The Examiner has objected to the inclusion of "micrometer" in Claim 3. The specification recites that the thickness of the side should be expressed in "millimeters." Claim 3 has been amended to recite that the thickness is expressed in "millimeters."

In the Drawings:

Applicants have cancelled the language in Claim 1 that referred to the contact between fin and side wall of the beam. Thus no amended drawing is required.

In the Claims:

Please cancel Claim 5 and amend the other pending Claims as set forth in the Appendix attached hereto.